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The following are the papers presented from this work:

I) **INCREASE IN ADHESION OF REFRACTORY OXIDE THIN FILMS BY CHOPPING.**

P.V.Patil, U.V.Nerle,R.K.Puri, Vijaya Puri.

Proceeding of seminar on `Commercial materials and industrial application'. P.14-17, July 1993.

II) **MECHANICAL AND OPTICAL PROPERTIES OF VACUUM EVAPORATED CHOPPED AND NONCHOPPED CERIUM OXIDE THIN FILMS.**

Puri R.K., Vijaya Puri,Nerle U.V., Patil P.V.

Paper presented at `National Symposium Of Vacuum Science And Technology'. Oct.1993.

III) **IMPROVEMENT IN MECHANICAL PROPERTIES OF CERIUM OXIDE THIN FILM BY CHOPPING.**

Vijaya Puri, R.K.Puri, P.V.Patil,U.V.Nerle.

Paper accepted for presentation in international conference on `Metallurgical Coatings And Thin Films.' California USA. April 1994.